

Amendments to the Specification

Please replace the paragraph at page 4, lines 18 to 25, with the following rewritten paragraph:

--An outstanding achievements directed by Jyh-Jier Ho et al. on research of Above-knee Prosthesis sensors for vertical pressures has been reported on *International J. of Electronics* (vol. 87, No.6, pp.757-767, 2000), but as to the study of Shear-Stress sensors, most of the abroad scholars are applying them in measuring Shear-Stress in the fluid field, emphasizing their high sensitivity despite of their measuring range of only a few Pa. Seeing this, it is apparent that this kind of sensors are not suitable for measuring the Shear-Stress between the stump skin and the socket on it.--

Please replace the paragraph at page 9, lines 9 to 12, with the following rewritten paragraph:

--The Invention, the Contact-type Micro Piezoresistive Shear-Stress Sensor shown ~~show~~ as Figures 2. includes two X-shape piezoresistors, ~~each with flanges at four ends,~~ as the primary sensing units. These sensing units consist vertically of: (from bottom to top)--

Please replace the paragraph at page 11, lines 21 to 23, with the following rewritten paragraph:

--(2) Implant the X-shape piezoresistors between ~~in~~ the middle of each side and ~~at~~ the center of the square diaphragm, having a smaller Normal Pressure influence and a larger Shear-Stress sensitivity.--

Please cancel the Abstract of the Disclosure presently in the application and add the new Abstract of the Disclosure attached hereto as the last page of the Specification.